

**CLEAN VERSION OF AMENDMENTS**

**IN THE SPECIFICATIONS**

Please amend the paragraph which was inserted between paragraph 57 and paragraph 58 of Application originally filed by the Amendment filed on 24 June 2002, as follows:

It can be appreciated that the ink-jet printheads of the present invention can be manufactured by a process of etching a channel into a bottom side of a silicon substrate and etching a plurality of holes on a bottom of said channel of said substrate to perforate said substrate. It is noted that the substrate is a single integrated monolithic unit of preferably silicon, the silicon substrate having both the channels and the ink feed holes etched therein. Electrodes or signal lines are deposited on a top side of the substrate. Resistive material is deposited on the top side of the substrate electrically joining pairs of ends of electrodes that are located near each other. The nozzle plate is attached to the top side of the substrate. The nozzle plate is perforated by a nozzle holes, each nozzle hole being positioned directly above a resistive layer joining the ends of a pair of signal lines. The resistive layer can be square in shape or essentially circular or omega in shape. The holes perforating the nozzle plate have a small diameter on a top side of the nozzle plate and have a larger diameter on the bottom side of the nozzle plate where the nozzle plate attaches to the top side of the substrate.